

(Rev. 2-32) PATENT AND TRADEMARK OFFICE  
CHEMICAL-ORGANIC PLANARIZATION PROCESS FOR  
ATOMICALLY SMOOTH INTERFACES

## INFORMATION DISCLOSURE

## STATEMENT BY APPLICANT

(Use several sheets if necessary)

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Gerald T. Mearini and Laszlo Takacs

FILING DATE

May 24, 2001

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2874 1762

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER							DATE	NAME	CLASS	SUB- CLASS	FILING DATE IF APPROPRIATE
<i>[Signature]</i>	5	7	4	8	3	5	0	5/5/98	Pan et al	359	130	6/19/96
	6	2	0	5	2	7	0	3/20/01	Cao	385	24	9/23/99
	6	2	3	3	2	6	1	5/15/01	Mesh et al	372	32	6/9/99
	5	5	2	9	6	7	1	6/25/96	Debley et al.	204	190.34	7/27/94
	5	7	2	5	4	1	3	3/10/98	Malshe et al	451	41	5/6/94
	4	7	4	7	9	2	2	5/31/88	Sharp	204	191.11	3/25/86

## FOREIGN PATENT DOCUMENTS

DOCUMENT NUMBER	DATE	COUNTRY	CLAS S	SUB- CLAS S	TRANSLATIO N YES NO

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

<i>[Signature]</i>	Kumar, et al.; <i>Near-Infrared Bandpass Filter from Si/SiO<sub>2</sub></i> ; Multilayer Coatings; February 1999
	Suntola, T.; <i>Cost-Effective Processing by Atomic Layer Epitaxy</i> ; 1993
	Bachman, et al.; <i>Molecular Layer Epitaxy by Real-Time Optical Process Monitoring</i> ; Department of Materials Science and Engineering, North Carolina State University, 1997.
	H., Kawai, T. Tabata; <i>Atomic Layer Control of the Growth of Oxide Superconductors Using Laser Molecular Beam Epitaxy</i> ; 1997.
	Spiller, E.; <i>Smoothing of Multilayer X-Ray Mirrors by Ion Polishing</i> ; IBM Research Division, Thomas J. Watson; 1993.
	Puik, E.J., van der Wiel and Zeijlemaker, H, and Verhoeven, J.; <i>Ion Etching of Thin W Layers: Enhancing Reflectivity of W-C Multilayer Coatings</i> ; March 30, 1989.
	Nishizawa, J., Abe, H., and Kurabayshi, T.J. 132(5) (1985).
	Puik, E.J., et al.; <i>Appln. Surf. Sci.</i> 47 (1991) 251.
	Kloidt, A, et al.; <i>Thin Sol Films</i> , 228 (1993) 154.

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Imai, F., Kunimori, K., and Nōzoye, H; *Novel Epitaxial Growth Mechanism of Magnesium Oxide/Titanium Oxide Ceramics Superlattice Thin Films Observed by Reflection High-Energy Electron Diffraction*; November 8, 1993.

Kildemo, et al.; *Real Time Control of the Growth of Silicon Alloy Multilayers by Multiwavelength Ellipsometry*; 1996.

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